Introduction to: Rocket GET THE CHIPS YOU NEED Semi-custom MEMS Devices



Overview

- RocketMEMSTM: What is it?
- RocketMEMSTM vs. Custom
- How RocketMEMSTM works
- Features
- Moving forward & Next steps...



Your Situation

You need a pressure sensor.

Nothing on the market fits your needs.

Your options:

- Work with the sensor-that-doesn't-quite-

fit

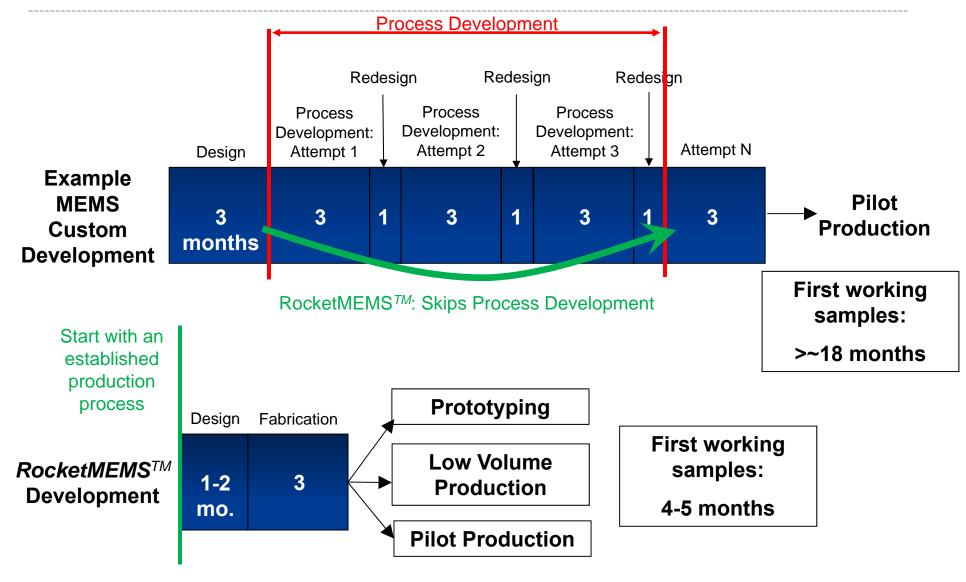
- Develop a custom pressure sensor
- Abandon the application

The *RocketMEMS*TM option

RocketMEMSTM delivers:

- Semi-custom bare die silicon pressure sensors
- Reduced cost
- Reduced time to market
- Reduced risk
- Pathway to large volume production

RocketMEMSTM vs. Custom Development



RocketMEMSTM: Design House-Foundry Cooperation



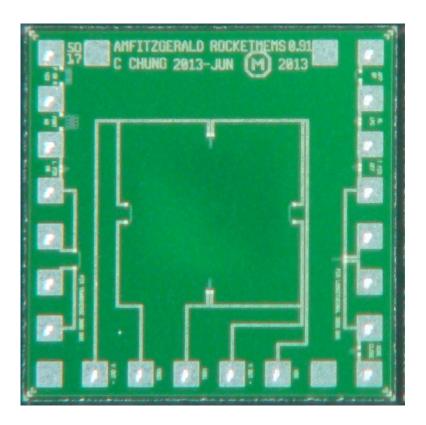


- Fixed, stable, established production process
- Design for manufacture
- No process development
- Fully characterized production process
- ISO certified, qualified foundry
- Many pressure sensor needs may be met without changing the process



RocketMEMSTM: Start with a great architecture

- Single crystal silicon membrane
 - Strong, high quality, stable material
 - Intrinsically free of hysteresis & creep
 - High burst pressure
- Silicon-on-Insulator (SOI) wafers
 - Precise membrane thickness
 - Consistent uniformity from device-to-device, run-to-run
- Piezoresistive transduction
 - Well understood
 - High sensitivity
- Low cost readout electronics
 - Simple Wheatstone bridge circuit
- 100% Test coverage for all guaranteed specifications



RocketMEMS[™] pressure sensor die (2 x 2 mm) with test structures

What can be customized?

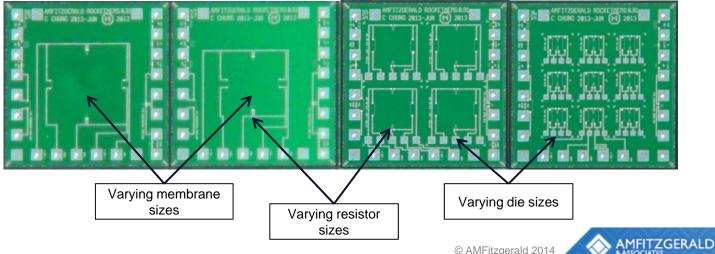
Customizable:

- **Pressure range**
- Sensitivity
- Die size & thickness
- **Bondpad location & size**
- **Bridge resistance**
- Full vs. Half bridge

Not customizable:

- Very high or low resistances
- Very wide dynamic range
- Very high sensitivities
- Very low noise

Examples of various RocketMEMSTM pressure sensors (with test structures)



Range of performance specifications

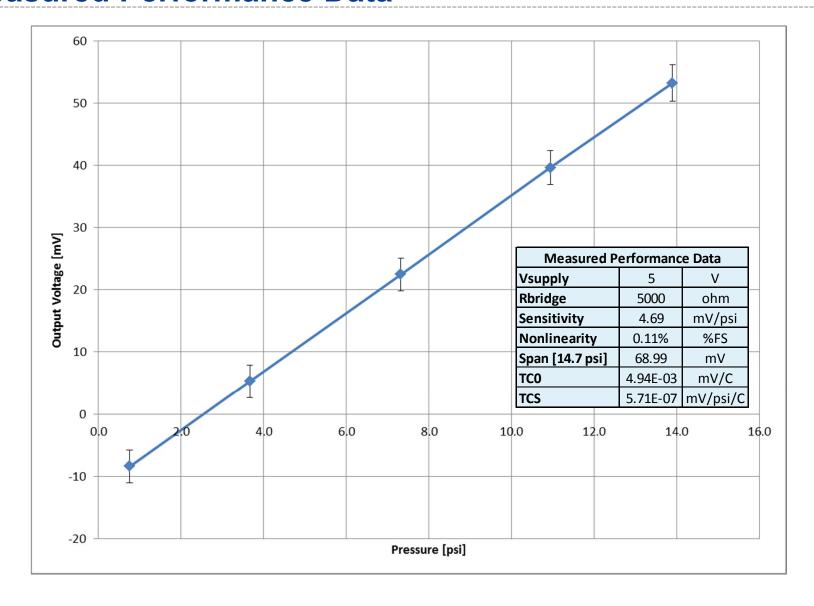
	Medical	Consumer Electronics	Industrial or Aerospace
Pressure range, absolute (atm)	0.2 - 0.5 (38-380 mmHg)	0.2 – 2	0.2 – 10 (1.5-105 psi)
Resistor value (KΩ)	1 – 10	1 – 10	1 – 10
Chip length (mm)	1 – 4	0.5 - 4	0.33 - 6
Thickness (mm)	0.3 - 1	0.3 - 1	0.3 - 1

Please note: these are example specifications, and not the boundaries of process

Pressure sensor applications – some examples

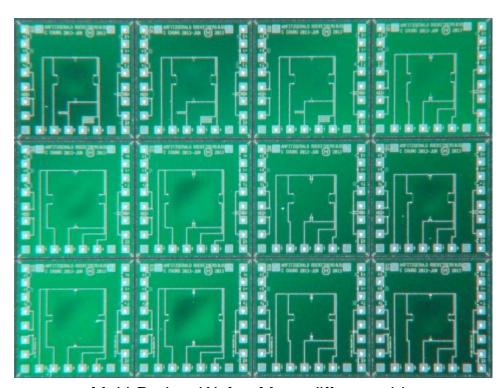
Medical	Consumer	Industrial or Aerospace
Blood pressure cuff	Altimeter (height)	Hydraulic systems
Flow measurement	Weather (barometers)	Fuel gauge
Monitors	Appliances	HVAC systems
Spirometer	Wristwatches	Engine control
CPAP machine	Sports equipment	Exhaust management
Catheters		Pitot tubes
Endoscopes		Monitors
Infusion pumps		
Physical therapy		

RocketMEMS™ Reference Pressure Sensor Measured Performance Data



Prototyping to high volume production

- Multiple designs on a run
 - Multi-Project Wafer (MPW)
- Scalable Production Volumes:
 - Rapid prototyping
 - 500+ devices
 - Low Volume Production
 - 10,000+ devices/year
 - High Volume Production
 - Millions of devices/year
- RocketMEMS[™]: a low-risk path to high volume production
 - Prototype on MPW runs
 - High volume dedicated runs at Silex



Multi-Project Wafer: Many different chip designs are processed on the same wafer

RocketMEMSTM: Our philosophy

"Design for Verified Process"

- No process development
- Other MEMS sensor types to be added to RocketMEMS soon





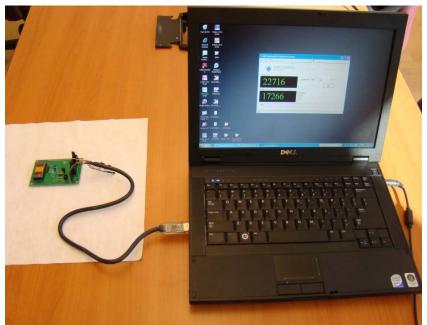
RocketMEMSTM: How it works

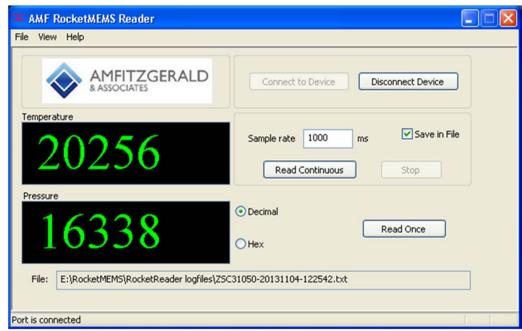
- Customer provides specification
- AMFitzgerald designs pressure sensors
- Silex Microsystems fabricates the chips
- Customer receives bare pressure sensor die in 4-5 months
 - On tape or in gel packs

Options: Readout electronics, ASIC, Packaging:

We can offer support and recommendations

Plug and Play Evaluation Kit with ZMDI ASIC





Kits include:

Readout with ZMDI ASIC & Board
Board-to-PC USB Cable
Software & Manual

Silex: the world leader in MEMS Manufacture



Accelerometers

Gyros

Pressure Sensors

Cantilevers

Touch Membranes

Flow Sensors

Filter Structures

CMOS Interposers

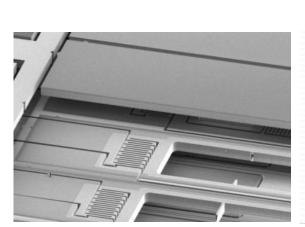
Needles

uBatteries

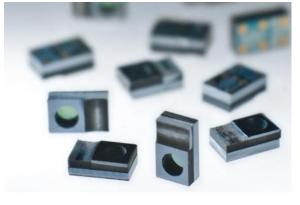
IR Sensors



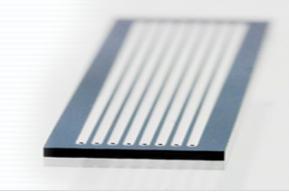
Pressure sensors for measuring blood pressure in coronary arteries



Mirrors for optical switching



Microphones for mobile telephones



Lab-on-chip for DNA analysis

Cell/DNA Analysis

Microphones

RF Switches

Lab-on-Chips

Print Heads

Drug Delivery Devices

Mirrors

Optical Benches

Oscillators

Silex Microsystems



- Dedicated MEMS foundry with 12 years of volume MEMS production experience
 - Over 350 projects
 - Over 100 international customers
 - Work with over 50% of world's top 30 MEMS companies
- Bringing Innovation in Technology
 - Sil-Via® TSVs in consumer applications since 2006
 - Silicon interposers for all-silicon 2.5G packaging since 2006
 - Advanced wafer level packaging
 - Met-Via® Thick wafer metal TSVs since 2010
- Custom process integration to support the needs of MEMS innovators worldwide







AMFitzgerald Company Background

- MEMS product development firm
 - Global clientele
 - Over 125 clients served to date
 - Startups to Fortune 100 companies
- Headquarters in Burlingame, California
 - Silicon Valley, near SFO airport
- Consistent growth since founding
 - Founded in 2003
- Active member of the MEMS Industry Group



Headquarters in Burlingame, CA



Semi-custom Silicon Pressure Sensors

- Reduced cost
- Reduced risk
- Reduced time to market
- Scalable production volumes

For Inquiries, Samples, Evaluation Kits

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